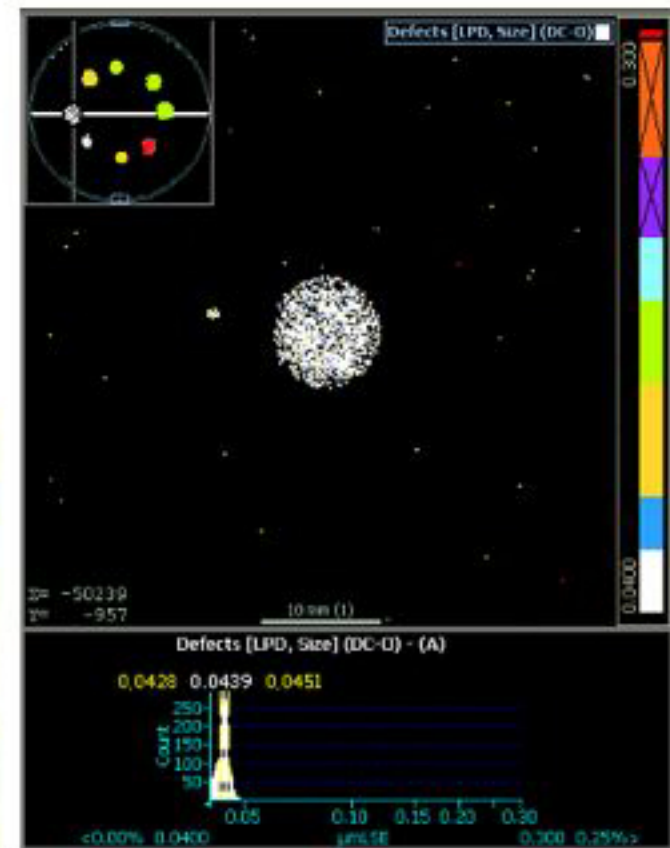


Model 2300 NPT-2 Automated Particle Deposition System

*Nano Particle Technology to Produce PSL Wafer
Standards & Particle Wafers for WET Process
Benches & Wafer Inspection Systems, 20nm-3 μ m*



**Dual Cassette FOUP for 300mm and 200mm Bridge
Applications; Recipe Control; 10 Quick Change
PSL Sizes; NIST SRM Calibration Mode; Exceeds
SEMI M52 Size Accuracy; Full, Spot, Ring
Depositions; CE Mark, SEMI S2, S8, S14**



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